

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants :Syouji NOGAMI et al. Group Art Unit : 2813
Appl. No. : 10/562,235 Examiner : Sonya D McCall Shepard
Filed : October 31, 2006 Confirmation No. : 8539
For : MANUFACTURING METHOD OF SEMICONDUCTOR WAFER AND
SEMICONDUCTOR WAFER MANUFACTURED BY THIS METHOD

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop **AMENDMENT**
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

This paper is responsive to the Examiner's Requirement for Restriction mailed from the Patent and Trademark Office March 20, 2009. Inasmuch as the Office Action sets a one-month shortened statutory period for response, to end April 20, 2009, no fee is believed due at this time. However, the Office is authorized to charge any required fee to Deposit Account No. 19-0089.

Remarks, including Applicants' Election with Traverse, begin on page 2 of this paper.